

Appl. Serial No.: 10/603,946
Amendment dated April 5, 2005
Reply to Office action of January 27, 2005

AMENDMENTS TO THE SPECIFICATION

Please amend paragraph 18 as follows:

-- (18) Preferably, but not necessarily, each of the MFCs 56 comprises a Pressure Insensitive type MFC (PiMFC) available from MKS Instruments of Andover, MA (<http://www.mksinst.com>). The PiMFC includes technology improvements in functionality and performance to help users in semiconductor and high purity thin-film applications increase tool throughput and reduce overall system costs. In particular, the PiMFC provides real-time accurate flow control, that is insensitive to upstream and downstream pressure disturbances, through advanced physical modeling and digital control algorithms. The PiMFC enables real-time control of process gas flow, accuracy and repeatability is significantly improved over conventional digital based MFCs, resulting in better chamber matching. A pressure insensitive mass flow controller is also disclosed in co-pending U.S. patent application serial number 10/178,721, filed June 4, 2002, and now U.S. patent no. 6,712,084, for an Apparatus and Method for Pressure Fluctuation Insensitive Mass Flow Control (~~Attorney Docket No. MKS-102~~), which is assigned to the assignee of the present invention and incorporated herein by reference.---